



## Compact and high efficiency micro-CPV module with high wafer utilization rate

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### ► To cite this version:

Corentin Jouanneau, Thomas Bidaud, Maxime Darnon, Gwenaëlle Hamon. Compact and high efficiency micro-CPV module with high wafer utilization rate. IEEE 50th Photovoltaic Specialists Conference (PVSC 2023), Jun 2023, San Juan, Puerto Rico. hal-04119376

HAL Id: hal-04119376

<https://hal.science/hal-04119376>

Submitted on 6 Jun 2023

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# Compact and high efficiency micro-CPV module with high wafer utilization rate

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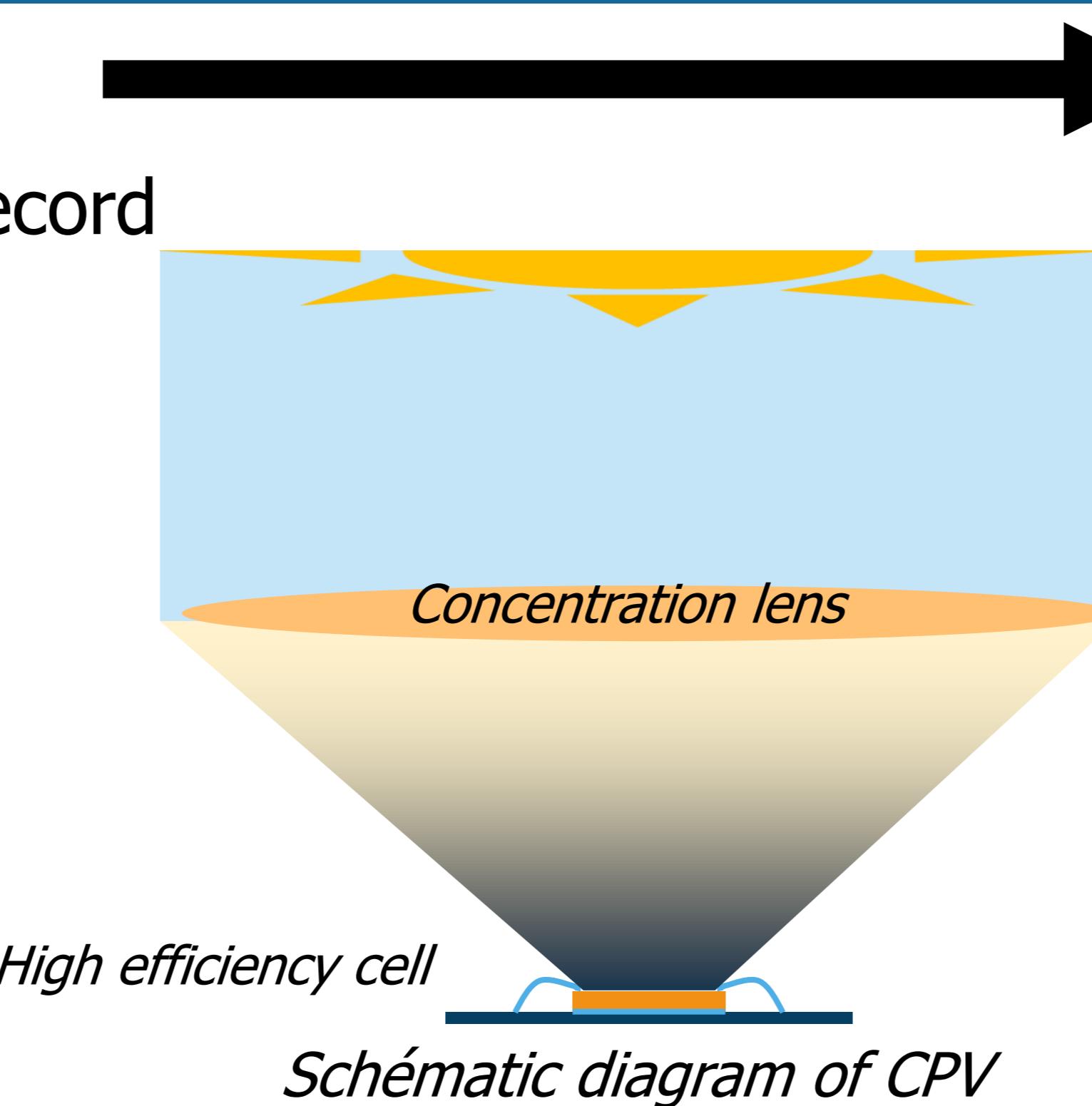
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## Context

### CPV

- Multi-junctions : Best performances (World record : 39,5% for a 3-junction cell at one sun [1]).
- Drawback : Price
- Add concentration lens to reduce amount of III-V materials used
- Drawbacks :
  - Compactness (~20cm thick)
  - Resistive and thermal losses
- **One of the most promising ways is the miniaturization**



### μ-CPV

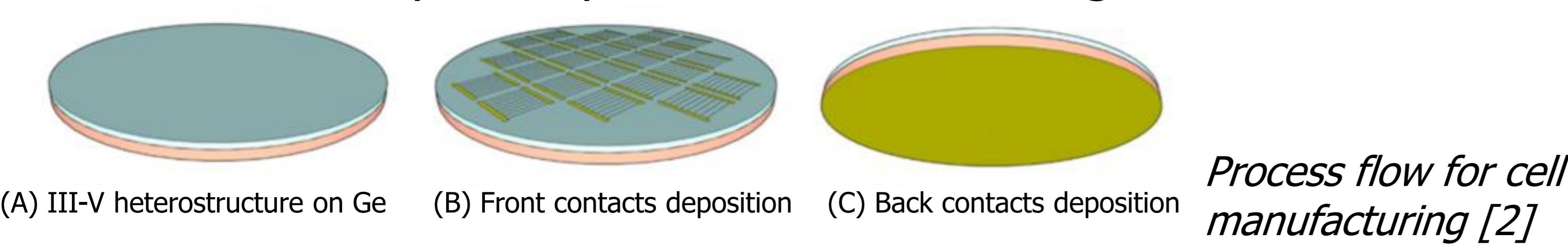
- Advantages of μ-CPV (cell size under 1mm<sup>2</sup>):
    - Compactness (few centimeters)
    - Price
    - Less resistive and thermal losses
  - Challenges of μ-CPV :
    - Perimetrical recombination
    - More cells per wafer so more losses during cutting
    - Shading increase when cell size decrease
- **We aim at fabricating compact and high efficiency μ-CPV module with high wafer utilization rate**

## Highlight

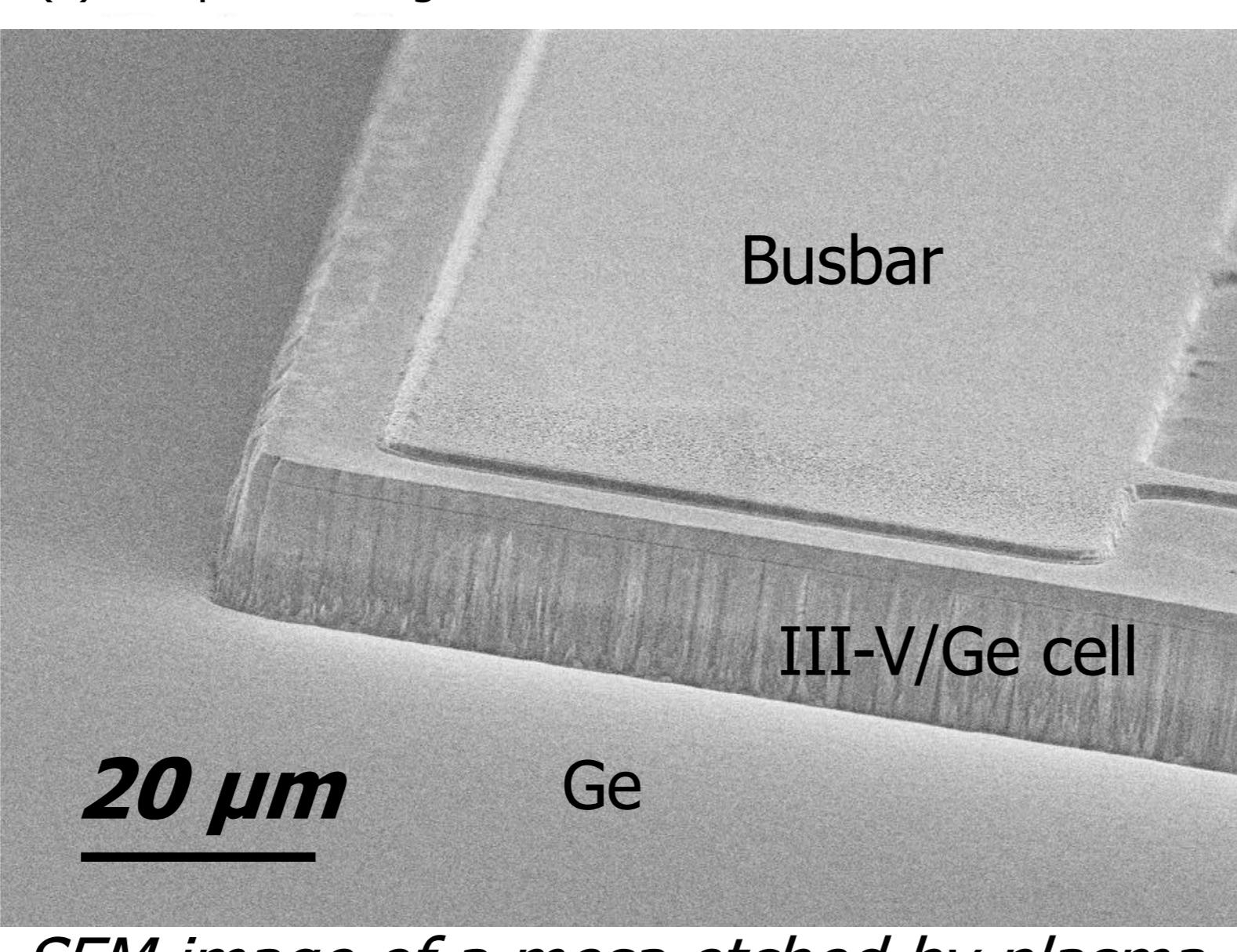
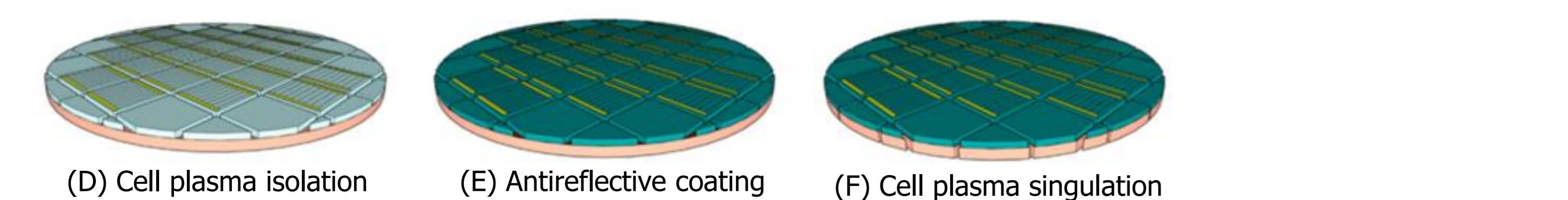
- **Plasma singulation : >90% utilization rate**
- **0,25mm<sup>2</sup> reach 31,26% efficiency at 1-sun**
- **Interconnection without busbars that increase the utilization rate**
- **High optics manufacturing tolerances**

## Fabrication of singulated submillimetric cells

- 6 standards steps except for isolation and singulation.



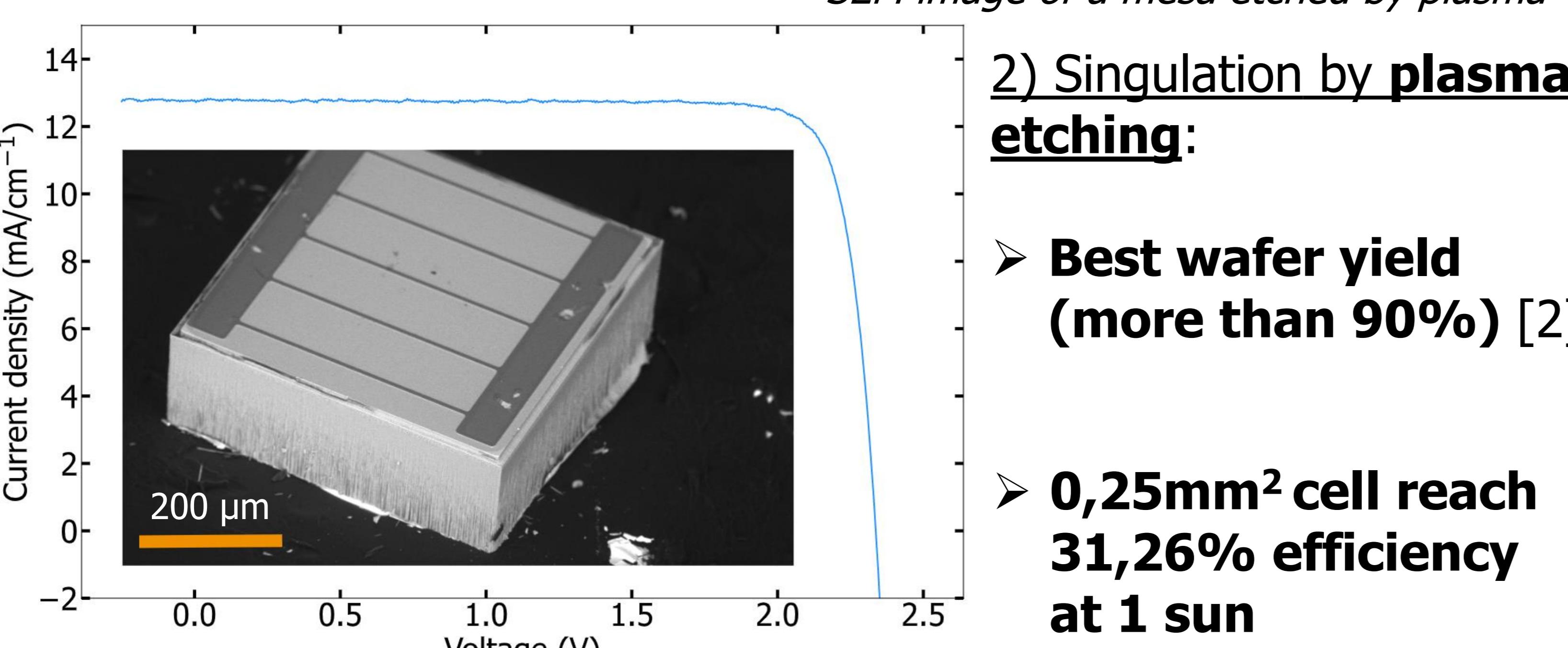
Process flow for cell manufacturing [2]



SEM image of a mesa etched by plasma

20 µm

Ge



### 2) Singulation by plasma etching:

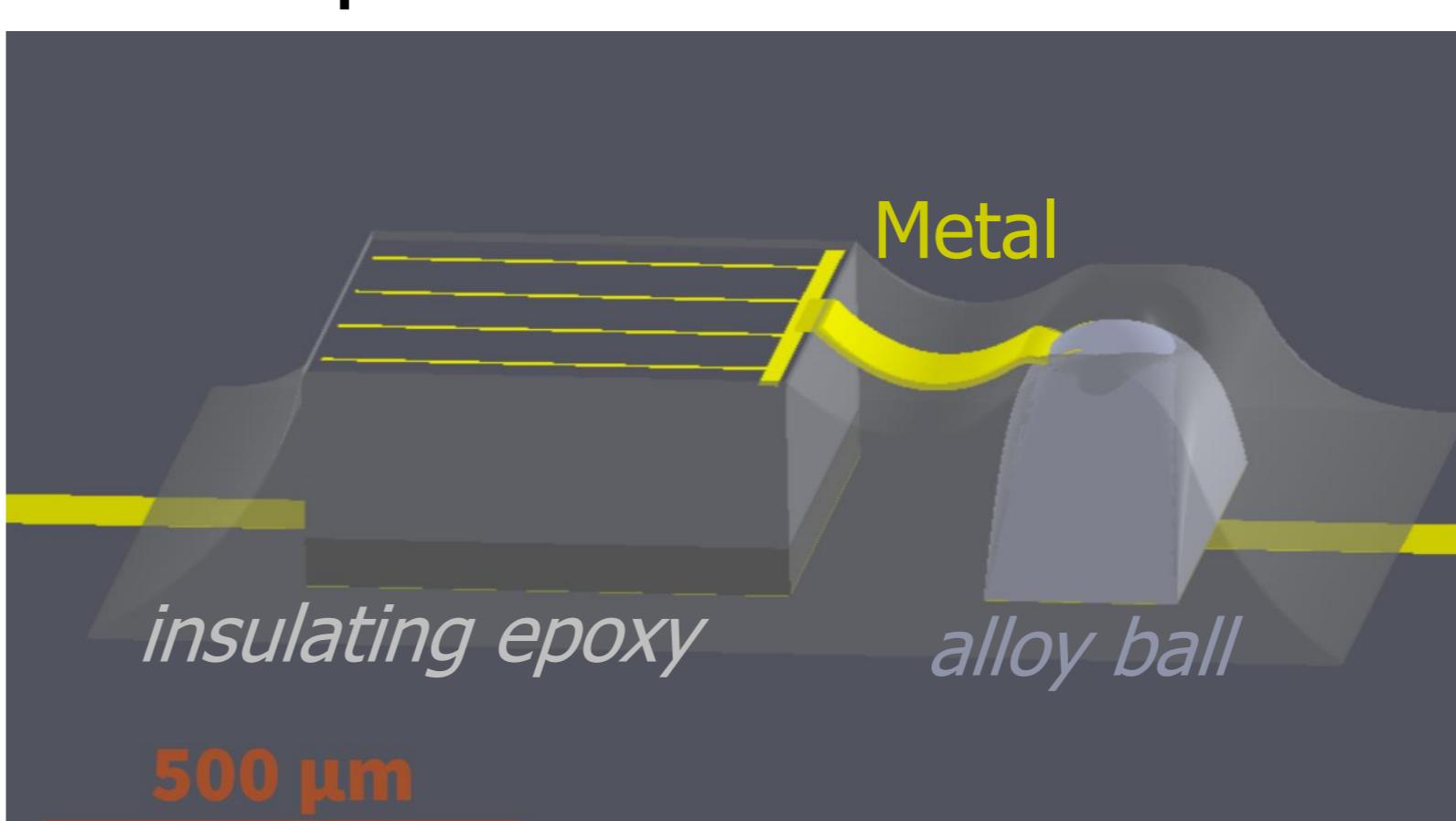
- **Best wafer yield (more than 90%) [2]**
- **0,25mm<sup>2</sup> cell reach 31,26% efficiency at 1 sun**

## Interconnexion of submillimetric cells

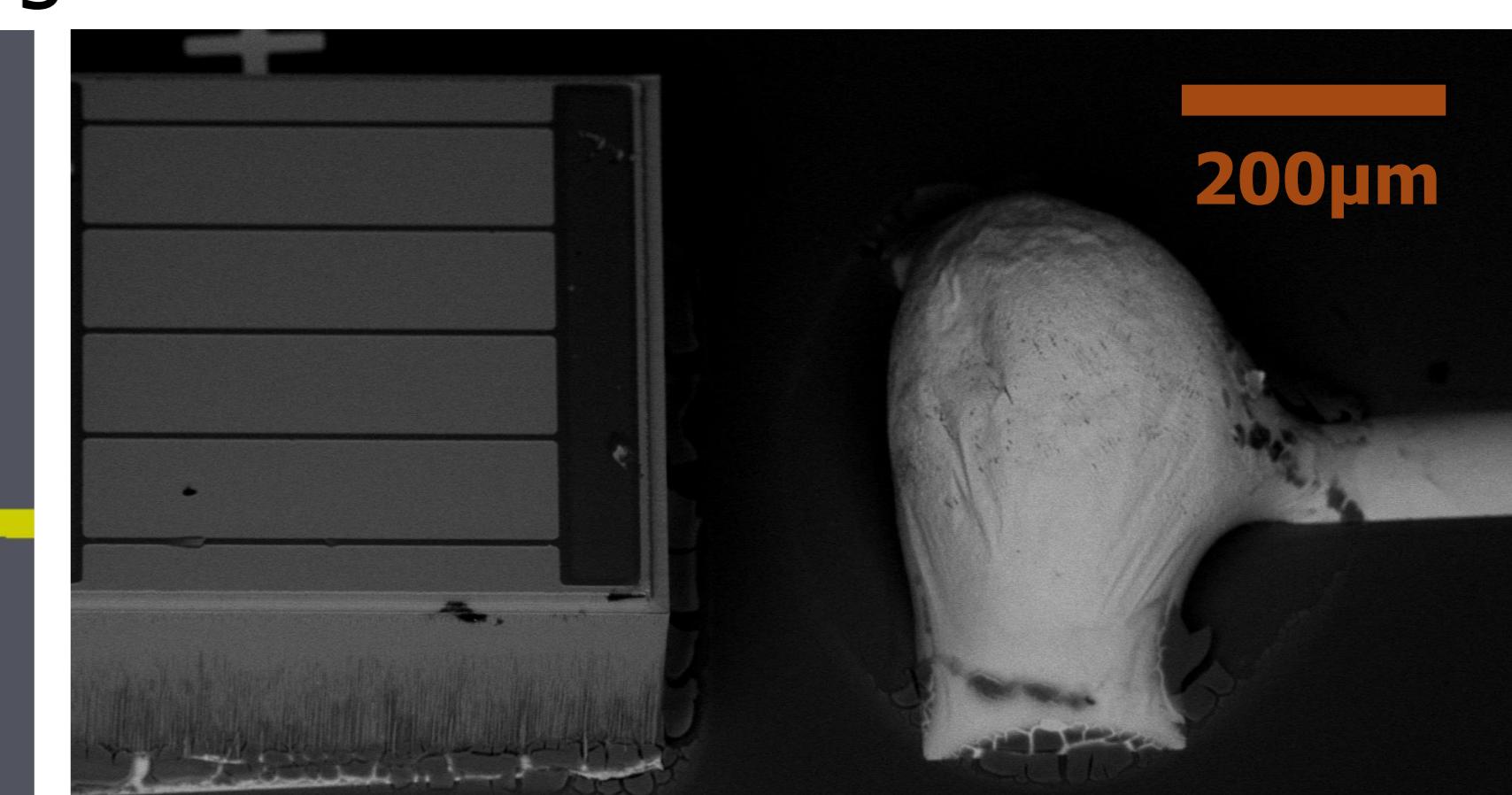
Interconnexion without wirebonding

- No busbars needed
- Important reduction in shading

### Improvement of wafer utilization rate

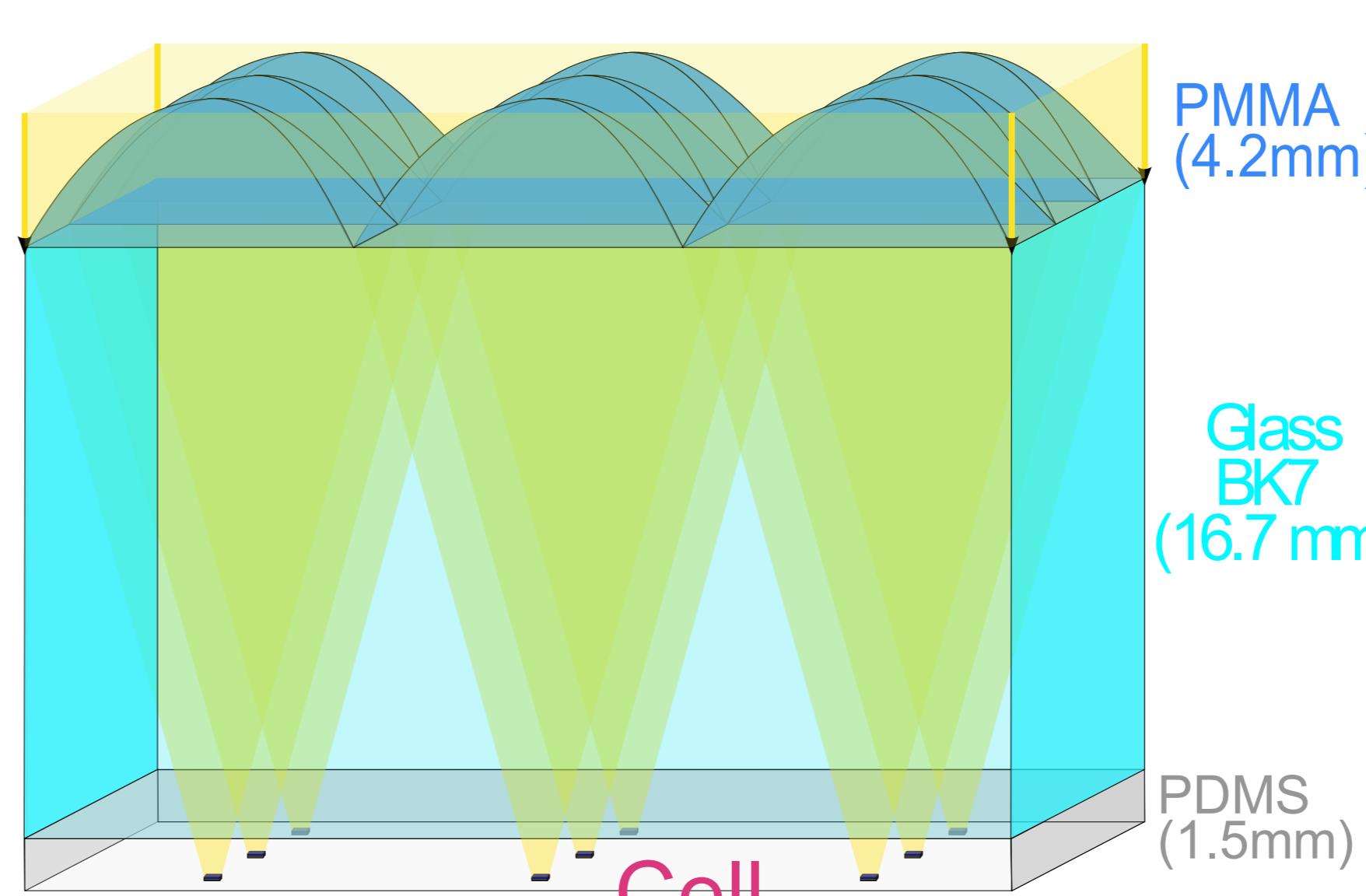


3D Diagram to scale of an interconnected cell.



SEM image of a 0.25 mm<sup>2</sup> cell singulated and the SAC305 ball welded on the substrate.

## Concentration optics for μ-CPV



3D drawing to scale of a micro-CPV module with 3 by 3 array of cells, bonded to glass BK7 substrate using PDMS. The light is focused on the cells by the POE optics disposed on the top glass surface.

POE curvature radius	± 70 µm
POE conicity constant	± 0.04
Cell misalignment	± 50 µm
POE thickness	± 210 µm

Table of manufacturing tolerances calculated with ZEMAX simulations

## Perspectives

- Increase performance by improve the passivation of our sidewalls.
- Interconnection on several cells to make a receiver
- The receiver must be aligned with the optics to build a module

## References

- [1] Site NREL, chart 2023, consulté le 01/05/2023
- [2] Albert et al., « Miniaturization of InGaP/InGaAs/Ge solar cells for micro-concentrator photovoltaics », Prog. Photovolt. Res. Appl., 2021.
- [3] M. de Lafontaine et al. « Influence of plasma process on III-V/Ge multijunction solar cell via etching », Sol. Energy Mater. Cells juin 2019

## Acknowledgments



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